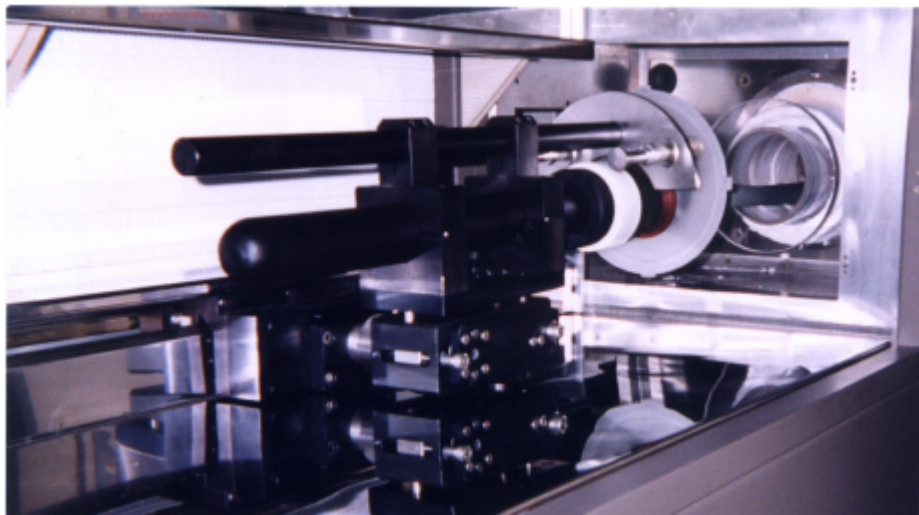


LYTOX[®]

Optimized system for thin oxides

The LYTOX[®] is a reduced pressure process system and cantilever which eliminates native oxide with uniformity lower than +/- 0.5%. The controlled pressure makes the process independent from the atmospheric pressure and enables better uniformities on wafers and run-to-run.



Features

- Combines the best features of atmospheric, LPCVD and MOCVD process
- Includes reactor tube, gas system, pump system, cantilever and door closure
- Adaptable to any brand of furnace
- Available for up to 200 mm wafers
- Liquid or gas source compatible for decontamination (DCE or Ph₃)

Advantages

- ◆ The only closed door & tube system capable to grow less than 100 Å oxide without any native oxide
- ◆ 10 times less gas (H₂, O₂) consumes compared with standard atmospheric steam oxidation process
- ◆ No influence from atmospheric pressure inside the leak tight tube thanks to close loop controlled pressure.
- ◆ Environment friendly : leak tight tube protects operator against TransLC, PH₃ or DCE use for decontamination